

IN THE CLAIMS

Please amend the claims as follows:

1. (Currently Amended) A cantilever, comprising:

a probe part scanning an observed sample and an electrode part supporting said probe part, wherein

said probe part includes:

an insulator having a sharp-pointed solid ~~shape~~ tip and

a conductive wiring which is placed on a part of a side surface of said insulator, having one end reaching a peak of said solid ~~shape~~ tip and an opposite end reaching said electrode part.

2. (Original) The cantilever according to claim 1, wherein said conductive wiring is placed so as to be shortest in length.

3. (Currently Amended) A manufacturing method of a cantilever, comprising the steps of:

(a) forming a hole having a sharp-pointed solid ~~shape~~ tip in a surface of a substrate so that a peak is formed inside of said substrate;

(b) forming a sacrifice film to cover said surface of said substrate and a side surface of said hole having said solid ~~shape~~ tip;

(c) forming a conductive wiring in a side surface part of said hole having said solid ~~shape~~ tip on said sacrifice film so that one end reaches a peak of said hole having said solid ~~shape~~ tip;

(d) forming an insulator having a selective etching rate to said sacrifice film to fill up

said hole having said solid ~~shape~~ tip after said step (c);

(e) forming an electrode part to cover an upper surface of said insulator, an opposite end of said conductive wiring and said sacrifice film; and

(f) separating said insulator, said conductive wiring and said electrode part from said substrate by etching said sacrifice film after said step (e).

4. (Currently Amended) The manufacturing method of the cantilever according to claim 3, wherein said step (c) includes the step of:

forming said conductive wiring so that the length from said sharp point of said hole having said solid ~~shape~~ tip to said surface of said substrate becomes shortest.